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Bib Data Sheet

CONFIRMATION NO. 5893

SERIAL NUMBER 09/836,857	FILING DATE 04/17/2001 RULE	CLASS 427 246	GROUP ART UNIT 1762 1	ATTORNEY DOCKET NO. 12179-P098US
APPLICANTS Seiichi Iwamatsu, Nagano, JAPAN;				
** CONTINUING DATA ** <i>None</i>				
** FOREIGN APPLICATIONS ** <i>None</i>				
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** SMALL ENTITY ** ** 06/14/2001				
Foreign Priority claimed	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	35 USC 119 (a-d) conditions met	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after	STATE OR COUNTRY JAPAN
Verified and Acknowledged	Allowance <i>[Signature]</i> Examiner's Signature	Initials <i>[Initials]</i>	SHEETS DRAWING 6	TOTAL CLAIMS 14
INDEPENDENT CLAIMS 2				
ADDRESS Winstead Sechrest & Minick P.C. 5400 Renaissance Tower 1201 Elm Street Dallas, TX 75270				
TITLE Electron beam duplication lithography method and apparatus				
FILING FEE RECEIVED 420	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			
<input type="checkbox"/> All Fees				
<input type="checkbox"/> 1.16 Fees (Filing)				
<input type="checkbox"/> 1.17 Fees (Processing Ext. of time)				
<input type="checkbox"/> 1.18 Fees (Issue)				
<input type="checkbox"/> Other _____				
<input type="checkbox"/> Credit				